



# Nanoparticle Knudsen Layers in Gases

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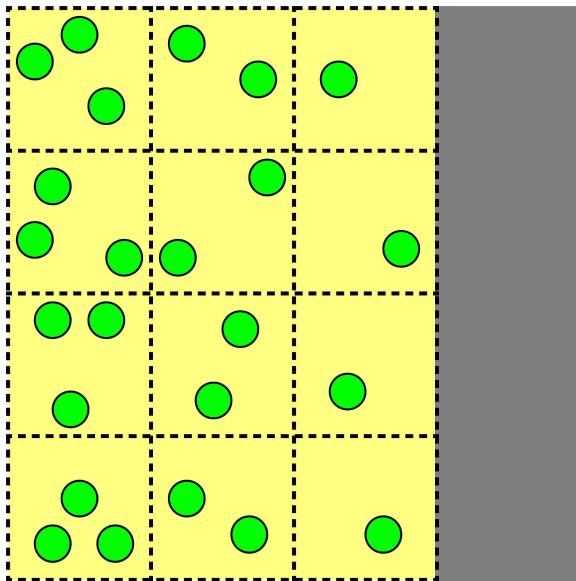
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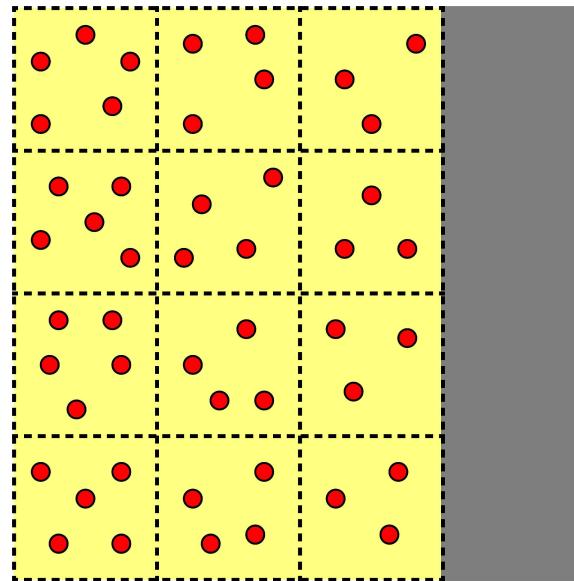
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# Nanoparticle Knudsen Layer in Gas



**Large** particles diffusing to wall  
approach **zero** concentration



**Small** particles diffusing to wall  
approach **nonzero** concentration

**Nanoparticles in gas have a Knudsen layer at wall**

- Concentration doesn't vanish as for larger particles
- Concentration at wall proportional to particle flux

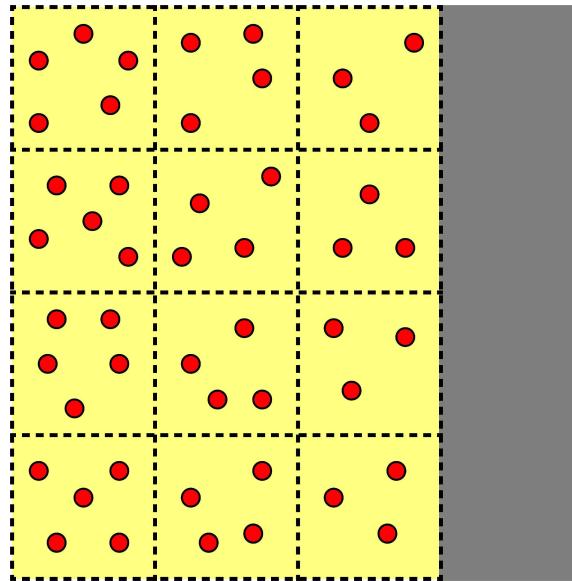
**Investigate using theory and simulations**



# Particle-Flux Boundary Condition

$$\hat{\mathbf{n}} \cdot \left( \mathbf{n} \mathbf{U} - D \frac{\partial \mathbf{n}}{\partial \mathbf{x}} \right) = \frac{n c f}{\pi^{1/2}}$$

Drift + Diffusion  $\propto$  Jump



## Particle-flux boundary condition as wall is approached

- Can be used in advection-diffusion transport analyses
  - Analogous to velocity-slip and temperature-jump BCs
- Concentration  $n$  extrapolated to wall proportional to flux
  - Drift velocity  $U$ , diffusivity  $D$ , thermal velocity  $c$
- Particle-flux coefficient  $f$  is dimensionless, order-unity
  - Depends on how particles stick to & reflect from wall



# Approximate Theory

$$\frac{\partial N}{\partial t} + \frac{\partial}{\partial \mathbf{x}} \cdot (\mathbf{u}N) + \frac{1}{\tau} \frac{\partial}{\partial \mathbf{u}} \cdot (-\mathbf{v}N) = \frac{c^2}{2\tau} \frac{\partial}{\partial \mathbf{u}} \cdot \left( \frac{\partial N}{\partial \mathbf{u}} \right), \quad \mathbf{v} = \mathbf{u} - \mathbf{U}$$

GFP equation

$$N = \frac{1}{\pi^{3/2} c^3} \exp \left[ -\frac{\mathbf{v} \cdot \mathbf{v}}{c^2} \right] \left( n_\infty + n_1 \exp \left[ \frac{2\mathbf{U} \cdot (\mathbf{x} - \tau \mathbf{v})}{c^2 \tau} - \frac{\mathbf{U} \cdot \mathbf{U}}{c^2} \right] \right)$$

exact solution

$$\int_{-\hat{\mathbf{n}} \cdot \mathbf{u} > 0} N(-\hat{\mathbf{n}} \cdot \mathbf{u}) d\mathbf{u} = \int_{\hat{\mathbf{n}} \cdot \mathbf{u} > 0} \mathcal{R}[\mathbf{u}] N(\hat{\mathbf{n}} \cdot \mathbf{u}) d\mathbf{u}$$

approximation at wall

$$\mathcal{f} = \mathcal{s} \left\{ 2 - \mathcal{s} \left( 1 + \operatorname{erf} \left[ \hat{U} \right] - \frac{1 - \exp \left[ -\hat{U}^2 \right]}{\pi^{1/2} \hat{U}} \right) \right\}^{-1}$$

sticking-fraction process:  $\mathcal{s}$

$$\mathcal{f} = \frac{\pi^{1/2} \hat{U} \left( 1 - \exp \left[ -\hat{U}_n^2 \right] \right)}{1 - \exp \left[ -\hat{U}_n^2 \right] - \exp \left[ -\hat{U}^2 \right] + \exp \left[ -\left( \hat{U}_n - \hat{U} \right)^2 \right] + \pi^{1/2} \hat{U} \left( \operatorname{erfc} \left[ \hat{U}_n - \hat{U} \right] + \operatorname{erfc} \left[ \hat{U} \right] \right)}$$

cutoff-velocity process:  $\sigma = 1 - \exp \left[ -\hat{U}_n^2 \right]$ ,  $\hat{U}_n = U_n / c$ ,  $\hat{U} = U / c$

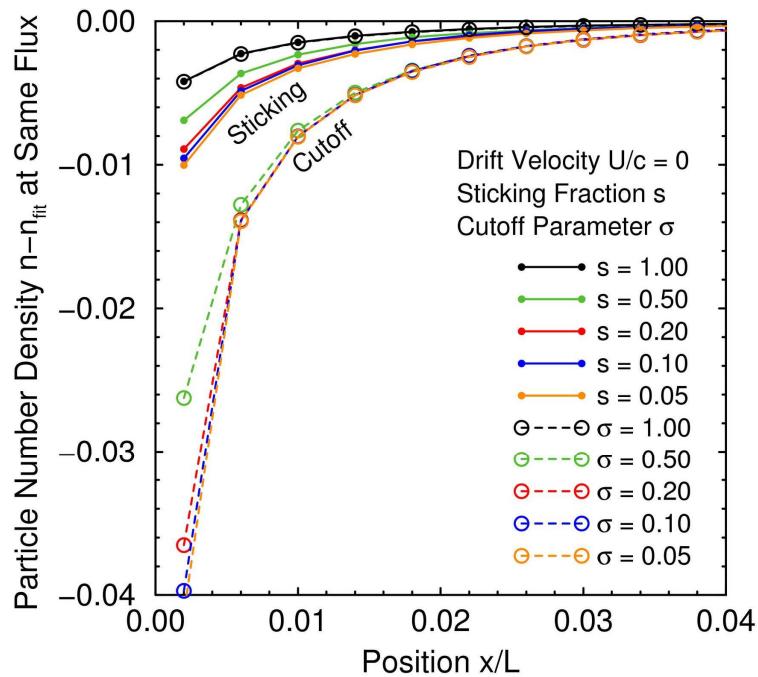
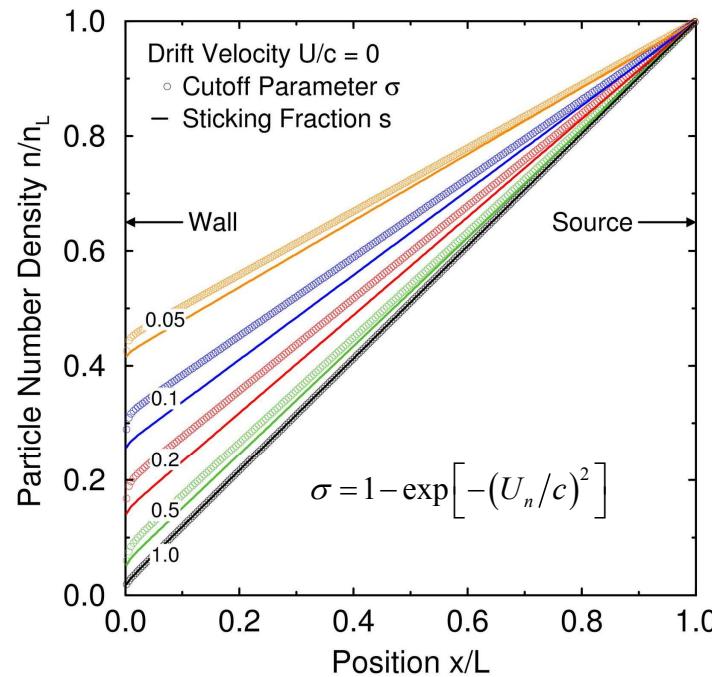
Generalized Fokker-Planck equation yields approximate particle-flux coefficient  $\mathcal{f}$  for arbitrary wall interactions

- Use exact solution for steady uniform unbounded space
- Approximation: outgoing equals reflected incoming at wall

Apply to two reflection processes  $\mathcal{R}$  with drift velocity  $\mathbf{U}$

- Sticking fraction: sticking probability  $\mathcal{s}$  same for all particles
- Cutoff velocity: stick if normal velocity  $< \mathcal{U}_n$  ( $\sigma$  is convenient)
- Any reflections are taken to be specular

# Langevin Simulations



## Langevin particle simulations: MP Ermak-Buckholz

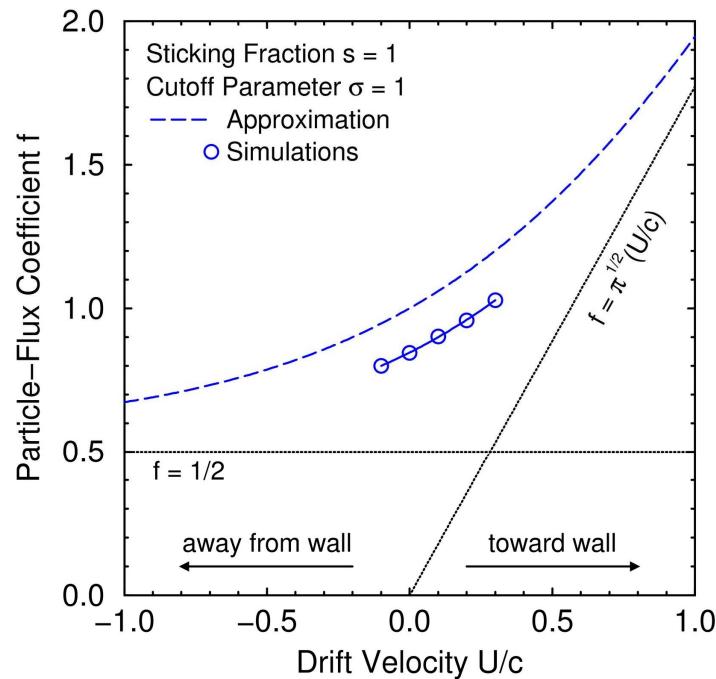
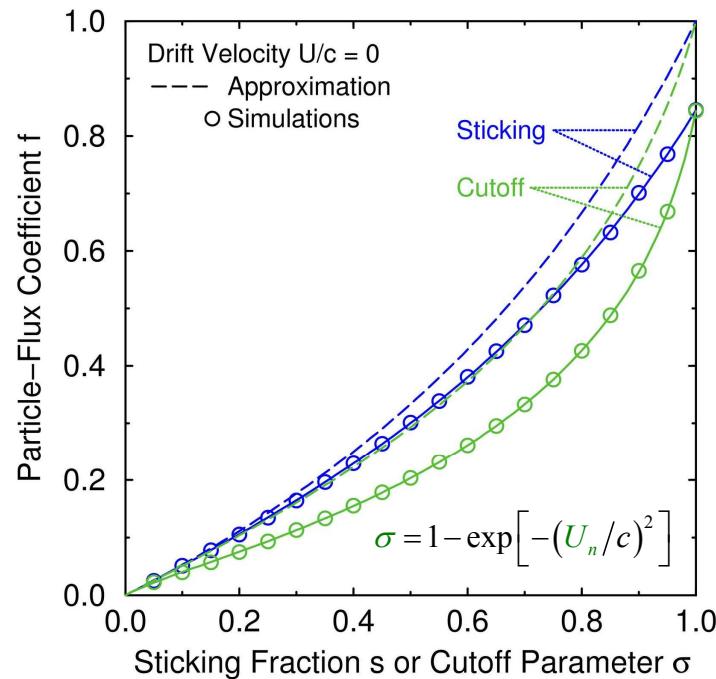
- 1D diffusion: wall at  $x = 0$ , source at  $x = L = 1000$  nm
- 20-nm PSL in air, 18-nm stopping distance (NIST, 2005)

## Knudsen layer near wall, linear profile away from wall

- Particle-flux coefficient  $f$  by extrapolating linear part to wall
- Cutoff  $\sigma$  ( $U_n$ ) has larger effect than sticking  $s$



# Particle-Flux Coefficient

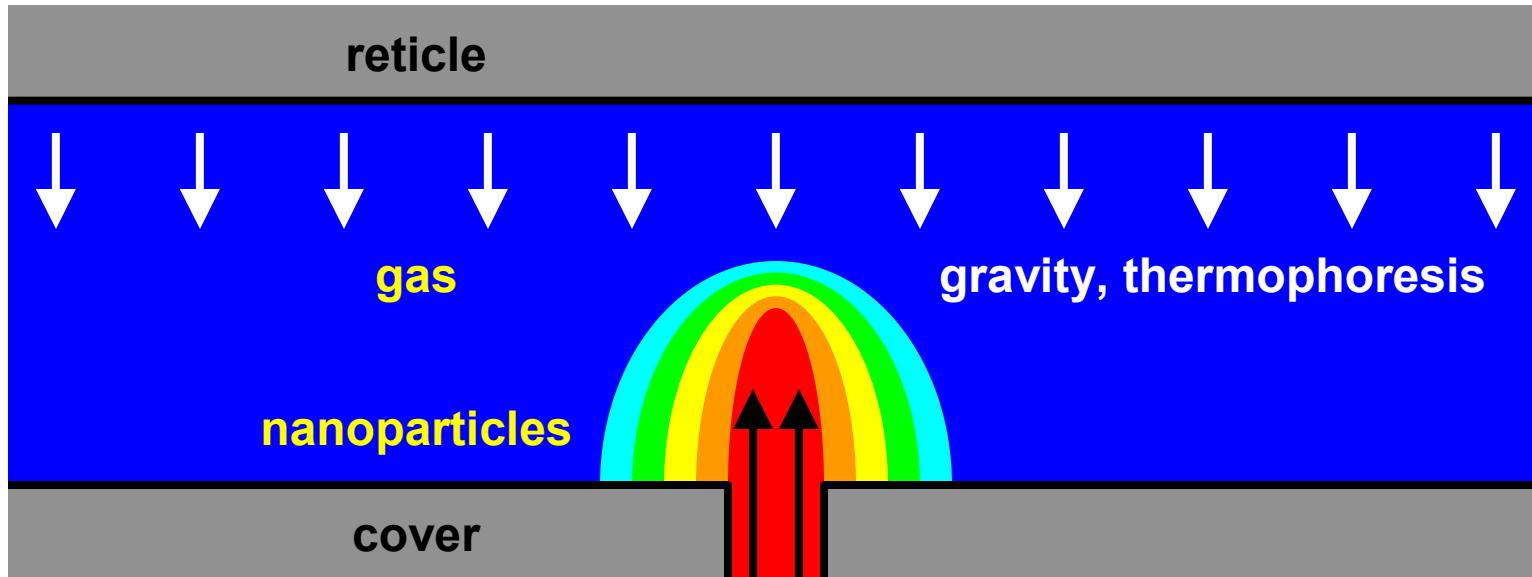


## Particle-flux coefficient $f$ from approximation & simulations

- Left: vs. sticking  $s$  or cutoff  $\sigma$  with drift velocity  $U = 0$
- Right: vs. drift velocity  $U$  with  $s = \sigma = 1$
- Approximation and simulations agree reasonably well
  - Better for sticking than cutoff: reflected particle distribution



# Semiconductor Application



**Assess contamination of reticle by nanoparticles in gas**

- Nanoparticles injected upward from below
- Nanoparticles repelled by gravity and thermophoresis

**Find probability that injected nanoparticle sticks to reticle**

- Advection-diffusion particle-transport analysis
  - Particle-flux boundary condition on solid surfaces
- Massively parallel Langevin particle simulations



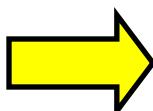
## Advection-Diffusion Analysis

$$\frac{\partial n}{\partial t} + \frac{\partial}{\partial \mathbf{x}} \cdot \left( n \mathbf{U} - D \frac{\partial n}{\partial \mathbf{x}} \right) = 0$$

advection-diffusion equation

$$\hat{\mathbf{n}} \cdot \left( n \mathbf{U} - D \frac{\partial n}{\partial \mathbf{x}} \right) = \frac{ncf}{\pi^{1/2}}$$

particle-flux boundary condition



$$H = U_I \tau, \hat{V} = \pi^{1/2} U/c, D = c^2 \tau/2$$

$$e_H = \exp[HU/D], e_L = \exp[LU/D]$$

$$P = \frac{f_2 \left( (e_H - 1) f_1 + \hat{V} \right)}{(e_L - 1) f_1 f_2 + (e_L f_1 + f_2) \hat{V}}$$

deposition probability

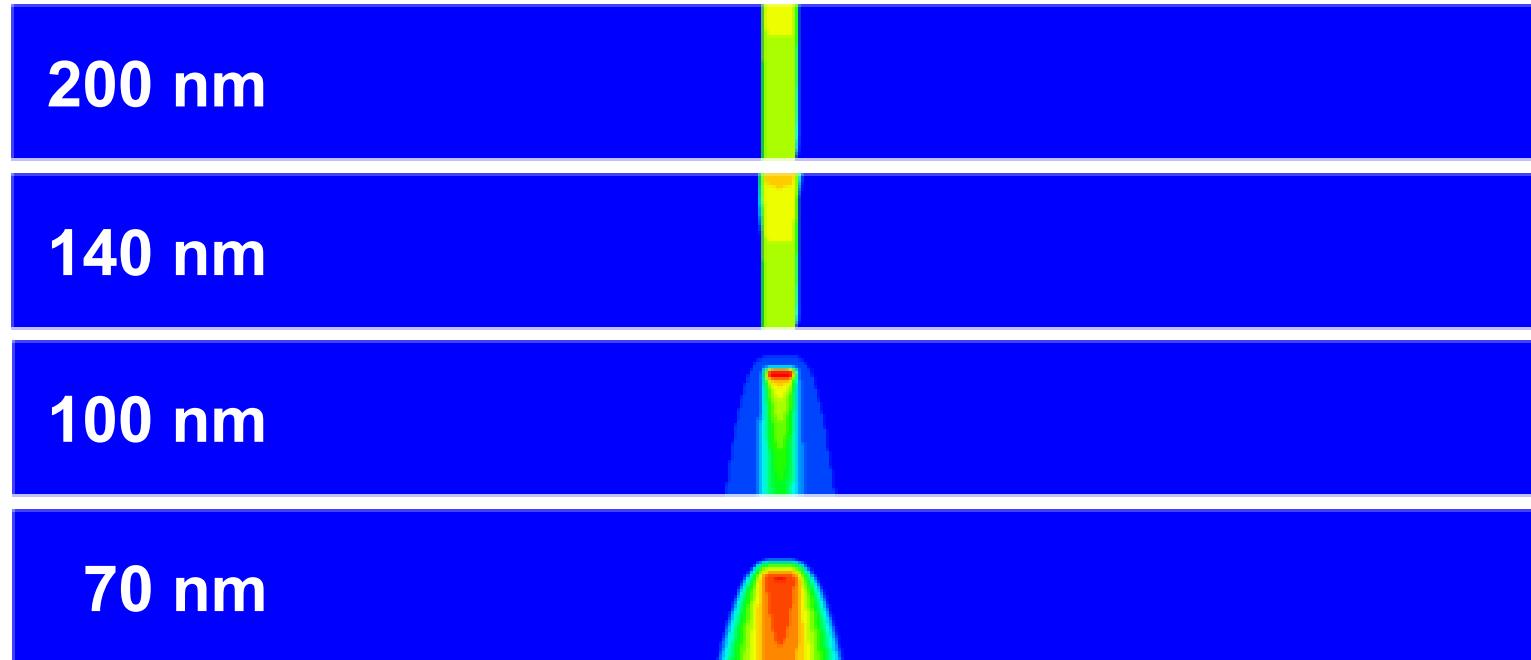
### Advection-diffusion analysis for deposition probability $P$

- Particles injected at speed  $U$ , “stop” at height  $H$  in gap  $L$
- Particles drift downward at speed  $U$  and diffuse with  $D$
- Particles stick with probabilities  $s_1$  &  $s_2$  on bottom & top
- Particle-flux coefficients  $f_1$  &  $f_2$  on bottom & top
- If  $H > L$ , reflect  $(1-s_2)$ , so  $H \rightarrow 2L-H$ ,  $P \rightarrow s_2 + (1-s_2)P$ , etc.

Above analysis does not provide deposition profile



## Typical Langevin Simulations



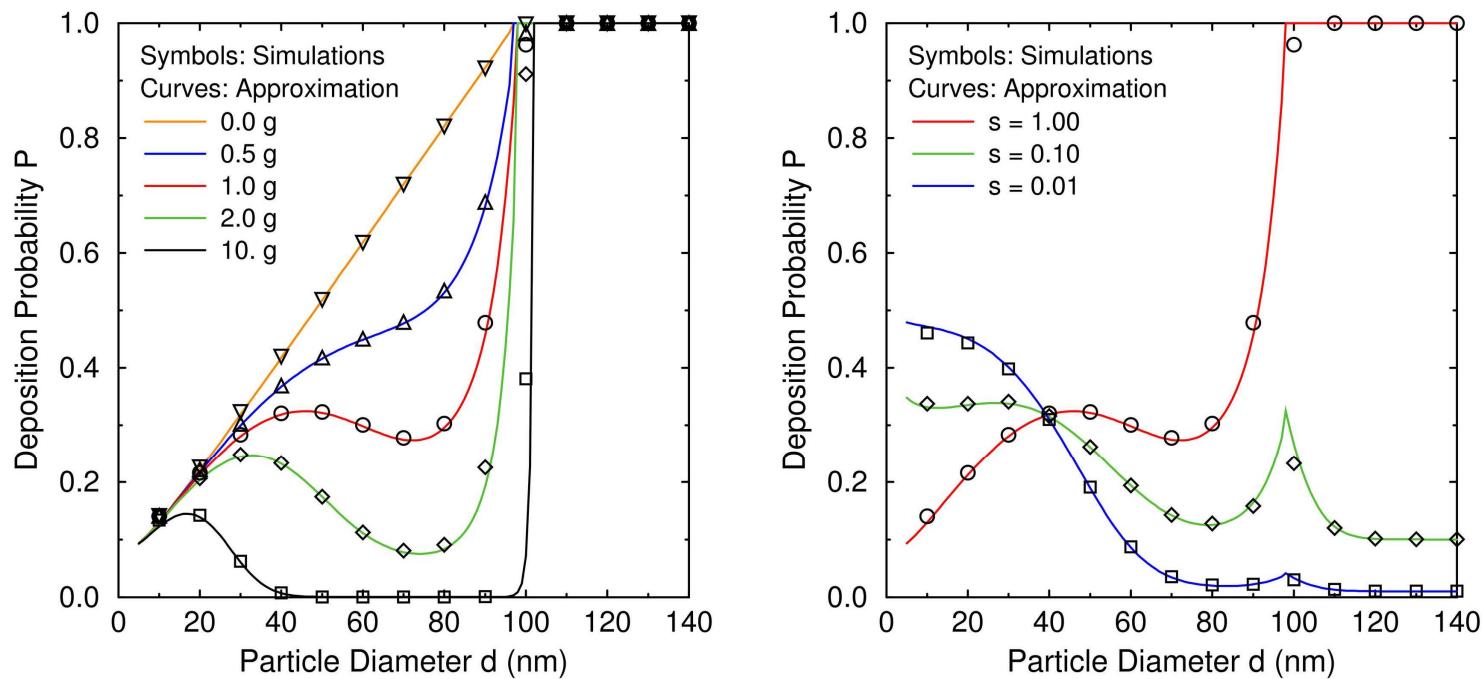
### Particle concentration fields for continuous injection

- Water-like particles in nitrogen at 50 mtorr and 295 K
- Gap height 1 cm, upward injection velocity 10 m/s
- Gravity 0g, temperature gradient 10 K/cm (thermophoresis)
- Sticking fraction  $s = 1$  on bottom and top

Diameters 70-200 nm, deposition probabilities 0-1



# Advection-Diffusion and Langevin



**Advection-diffusion and Langevin agree very well**

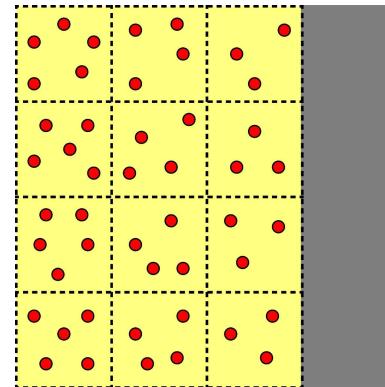
- Left: **gravity 0-10g with  $s = 1$  (thermophoresis is similar)**
  - “Bumps” at low diameter, where diffusion exceeds gravity
- Right: **sticking fraction  $s = 0.01, 0.1, 1$  with gravity 1g**
  - “Cusps” occur when penetration exceeds gap:  $H \geq L$
- In both cases, large diameter  $d$  yields  $P \rightarrow s$



# Conclusions

$$\hat{\mathbf{n}} \cdot \left( n\mathbf{U} - D \frac{\partial n}{\partial \mathbf{x}} \right) = \frac{ncf}{\pi^{1/2}}$$

Drift + Diffusion  $\propto$  Jump



**Nanoparticles in gas have Knudsen layer at wall**

- Particle concentration at wall proportional to flux
- Structure determined by reflection/sticking process

**Nanoparticle Knudsen layer investigated**

- Generalized Fokker-Planck equation
- MP Langevin particle simulations

**Particle-flux boundary condition developed**

- For advection-diffusion particle-transport analyses
- Uses particle-flux coefficient  $f$  from above



## Acknowledgments



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